

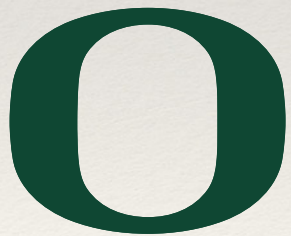


August 21, 2023

The SiD Digital ECal Based on Monolithic Active Pixel Sensors

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on behalf of
the SiD MAPS Collaboration
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Rota, C.Vernieri et al.)



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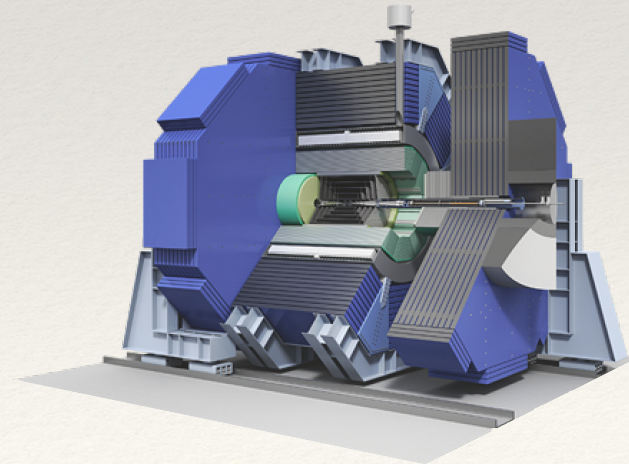
Research partially supported
by the U.S. Department of Energy

Ref: Brau JE, Breidenbach M, Habib A, Rota L, Vernieri C.
The SiD Digital ECal Based on Monolithic Active Pixel Sensors.
Instruments **2022**; 6(4):51.
<https://doi.org/10.3390/instruments6040051>



Introduction - MAPS for Linear Higgs factory ECal

- ❖ Higgs factory detectors need unprecedented precision.
- ❖ Ambitious physics goals demand challenging detector requirements on tracking and calorimetry.
 - ❖ High precision and low mass trackers,
 - ❖ Highly granular calorimeters.
- ❖ Monolithic Active Pixel Sensor (MAPS) technology offers needed advances.
- ❖ Sensors and readout circuitry are combined in pixels,
 - ❖ Fabricated with commercial CMOS processes.
- ❖ Currently MAPS widely used in HEP, astronomy and photonics,
 - ❖ Inner Tracking System Upgrade (ITS2) of ALICE at LHC.





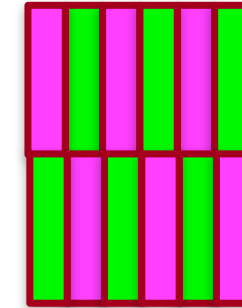
Potential Attributes - MAPS for Linear Higgs factory

- ❖ Small pixel (down to $\sim 10 \mu\text{m}$) \rightarrow High Granularity
- ❖ Small sensor capacitance (few fF) \rightarrow better performance for lower power consumption than hybrid detectors
- ❖ Low material budget \rightarrow The wafer can be thinned ($<100 \mu\text{m}$)
- ❖ Fast production \rightarrow no bump bonding necessary
- ❖ Relatively cheap solution, using commercial CMOS imaging technologies
- ❖ Possibility of large stitched sensor \rightarrow up to 30 cm x 10 cm
- ❖ Timing to $< \text{ns-rms}$ (with $<115 \text{ mW} / \text{cm}^2 \times \text{DutyFactor}$; $\text{DutyFactor} < 1\%$ for LC)

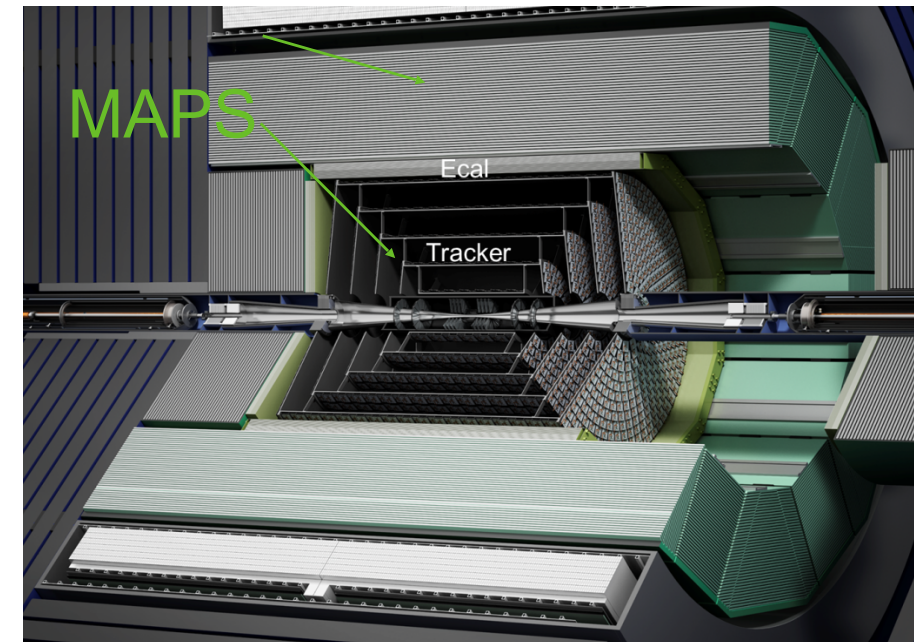
Noise \Downarrow Power \Downarrow Cost \Downarrow

Main specifications for Large Area MAPS development

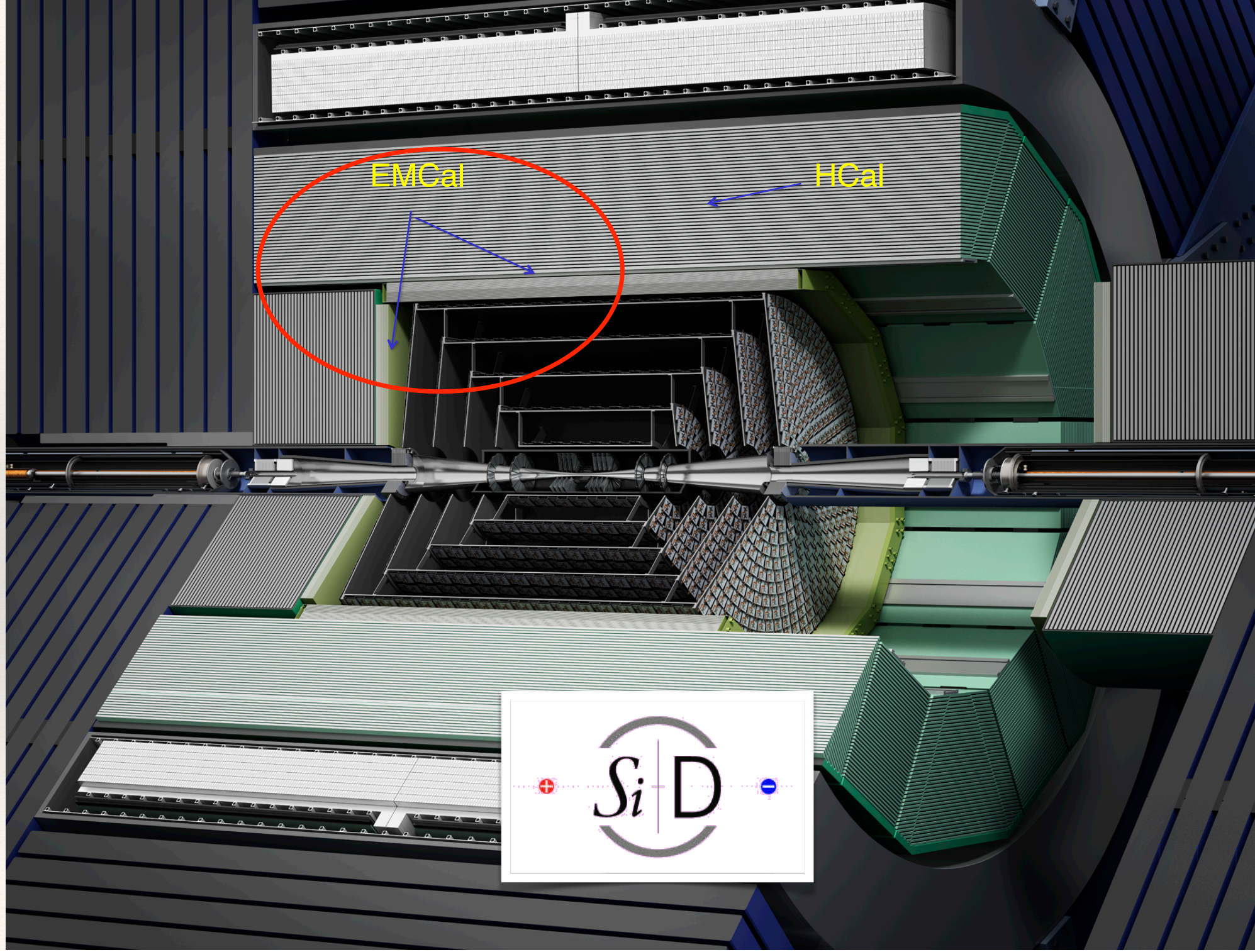
Parameter	Value	Notes
Min Threshold	140 e ⁻	0.25*MIP with 10 μm thick epi layer
Spatial resolution	7 μm	In bend plane, based on SiD tracker specs
Pixel size	25 x 100 μm ²	Optimized for tracking
Chip size	10 x 10 cm ²	Requires stitching on 4 sides
Chip thickness	300 μm	<200 μm for tracker. Could be 300 μm for ECal to improve yield.
Timing resolution (pixel)	~ ns	Bunch spacing: C ³ strictest with 5.3- >3.5 ns; ILC is 554 ns
Total Ionizing Dose	100 kRads	Total lifetime dose, not a concern
Hit density / train	1000 hits / cm ²	
Hits spatial distribution	Clusters	Due to jets
Balcony size	1 mm	Only on one side, where wire-bonding pads will be located.
Power density	20 mW / cm ²	Based on SiD tracker power consumption: 400W over 67m ²



25 x 100 μm²
ECal performance
same as
50 x 50 μm²



SiD Tracker and the ECal



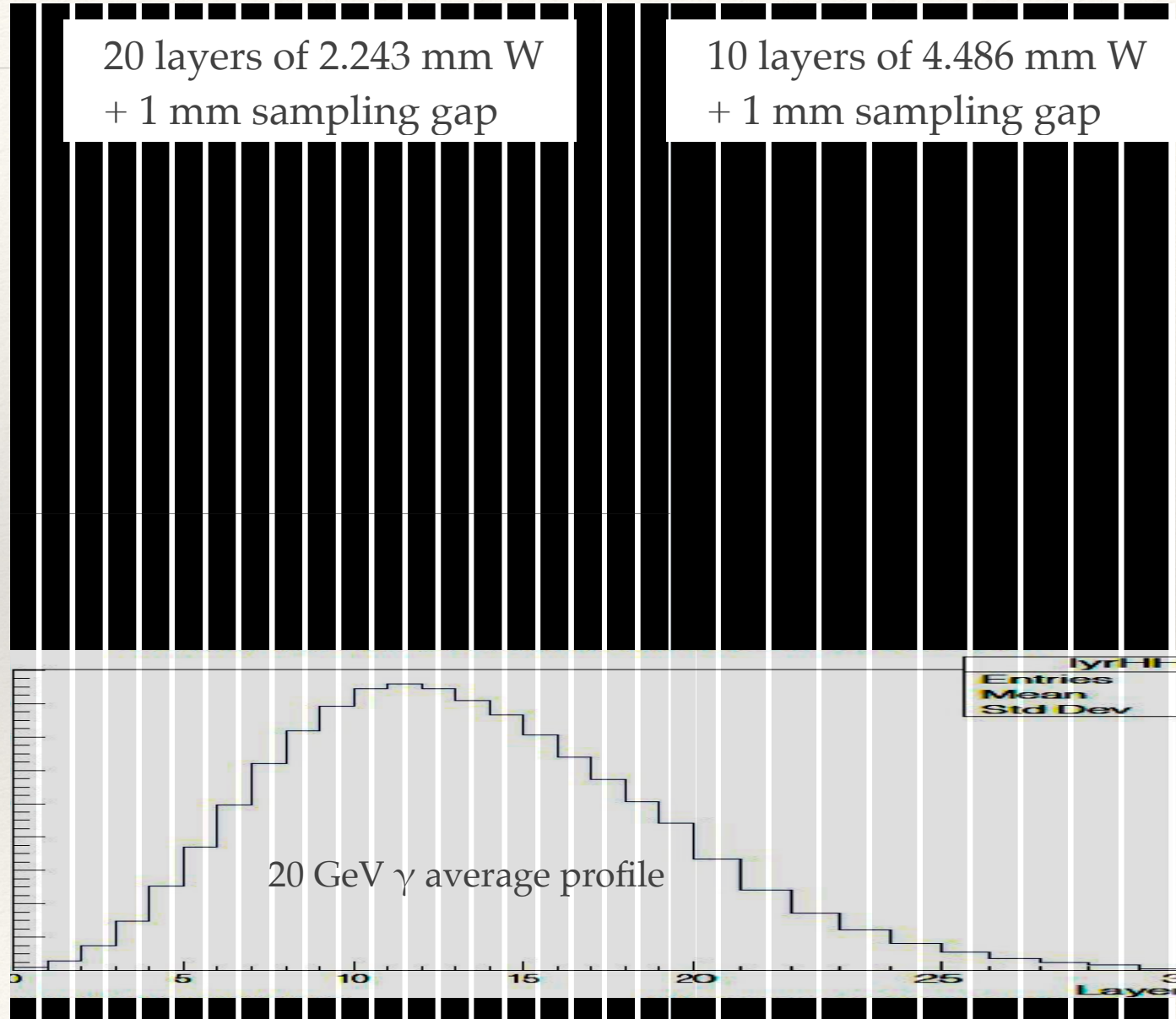
Longitudinal structure of SiD ECal



Total = $27 X_0$



Minimize sampling gap to achieve optimal Moliere radius and shower separation



Power during integration phase

Phase:



- Avg power reduced by power-cycling ... but **peak** current draw is not! current draw ~16 A
 - → significant voltage drop

Possible strategies:

- Bypass caps; EMCal flat cable distributes power; Re-distribution layer; more/thicker metal layers.

Need to investigate strategies on how to cope with shorts:

L. Rota

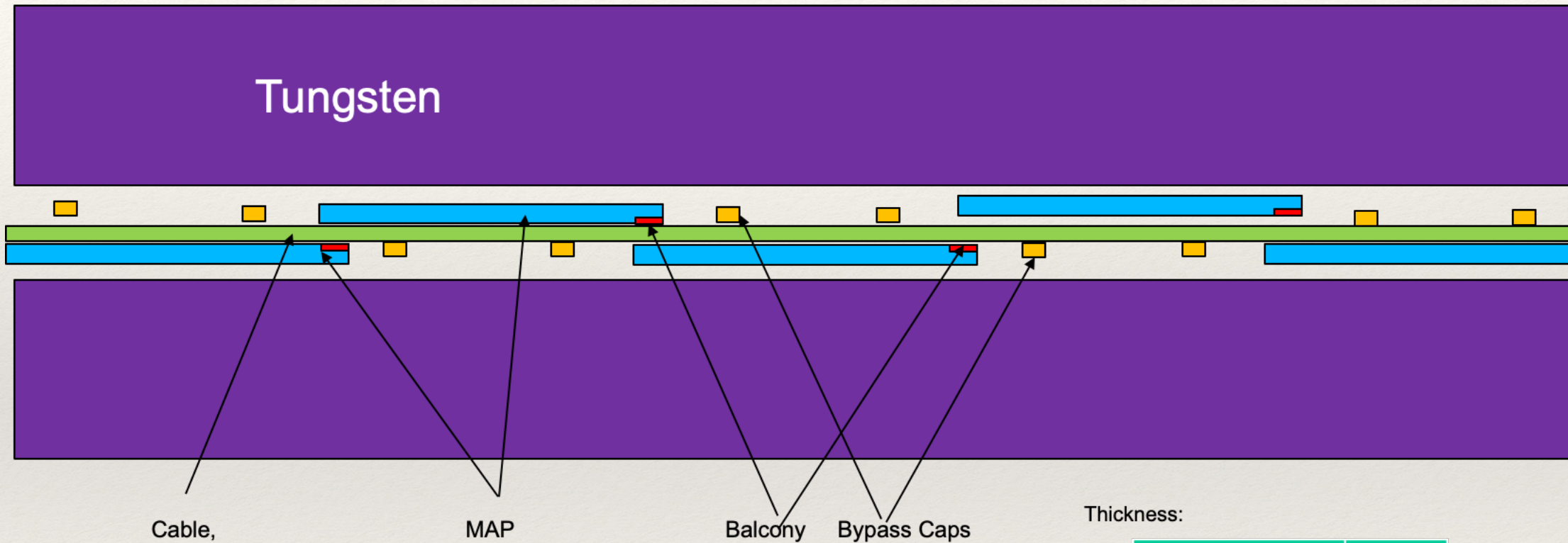
Power during readout phase

Asynchronous readout logic with **zero-suppression**:

- Only pixels with HIT information read out. **power** ↓
- Remove clock → **power** ↓

Gap Structure with MAPS

Not to scale



ONE CABLE IN GAP DESIGN

Gap structure with MAPs on one cable (or pcb). Requires bump bonding

This may well need adjustment following more cable design

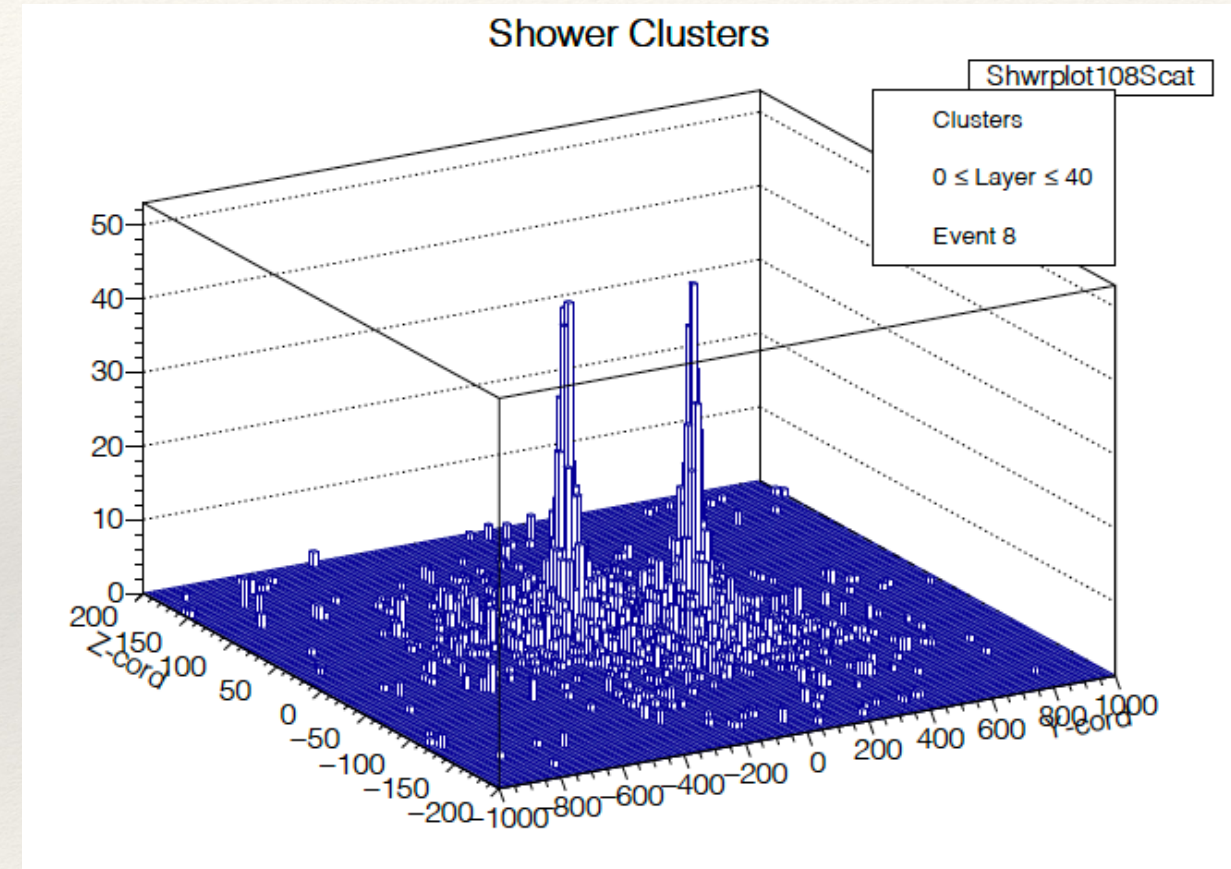
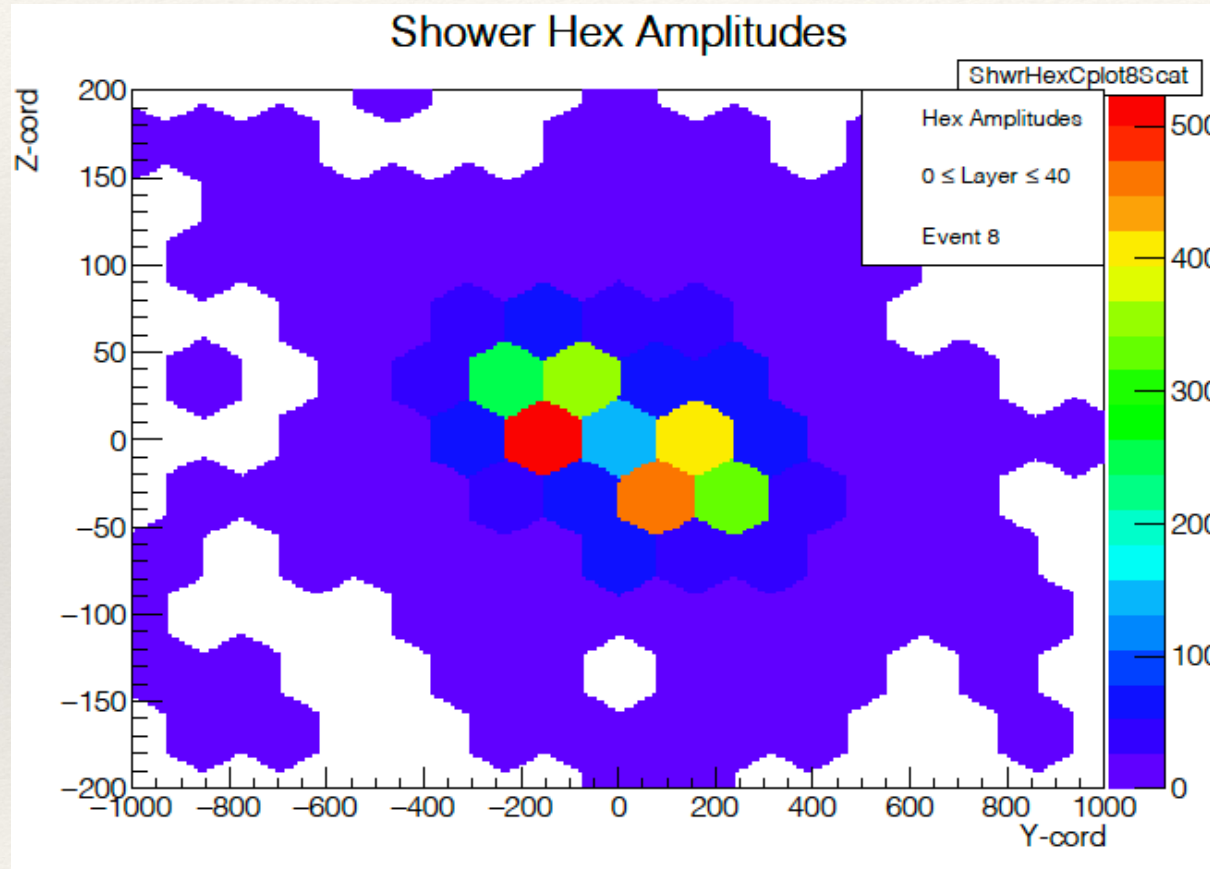
Thickness:

Middle Cable	400 μ
Top Sensor	200
Bottom Sensor	200
Bottom Cable	0
Total	800
Clearance with 1 mm gap	200

M. Breidenbach

Multi-shower of SiD MAPS compared to SiD TDR

40 GeV $\pi^0 \rightarrow$ two 20 GeV γ 's



SiD TDR {arXiv:1306.6329 [physics.ins-det]}
 hexagonal sensors - 13 mm² pixels

New SiD fine MAPS pixel sensors
 25 μm x 100 μm pixels

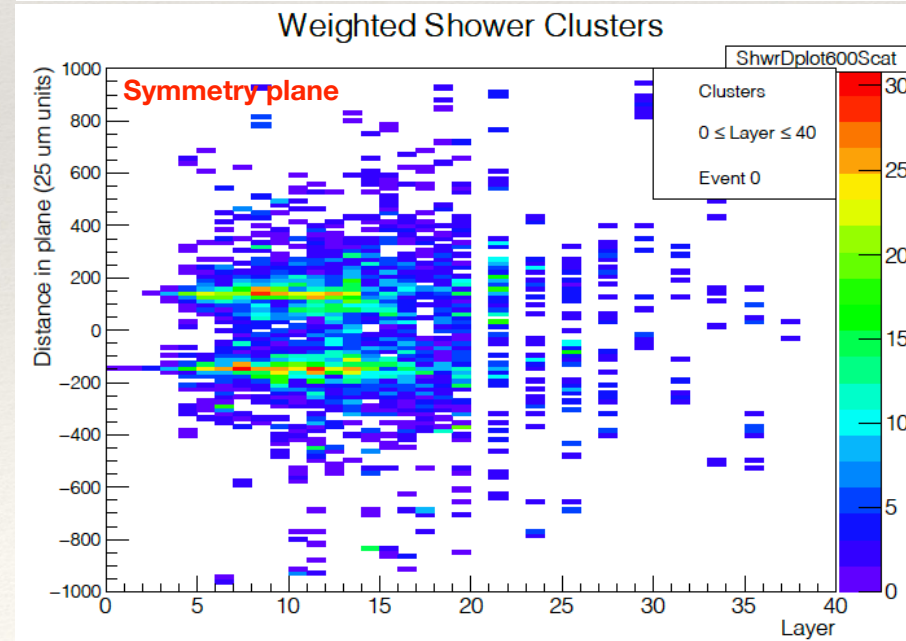
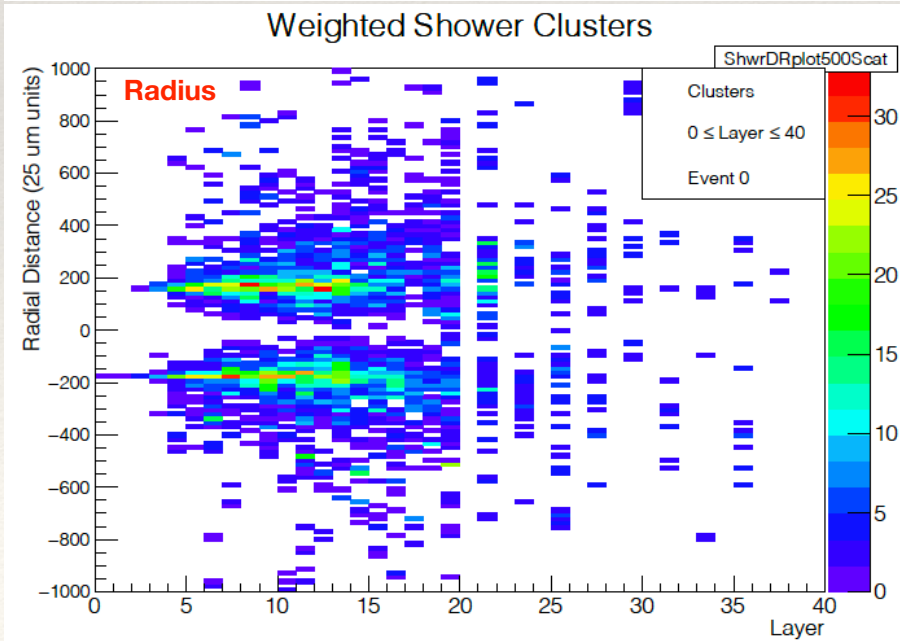
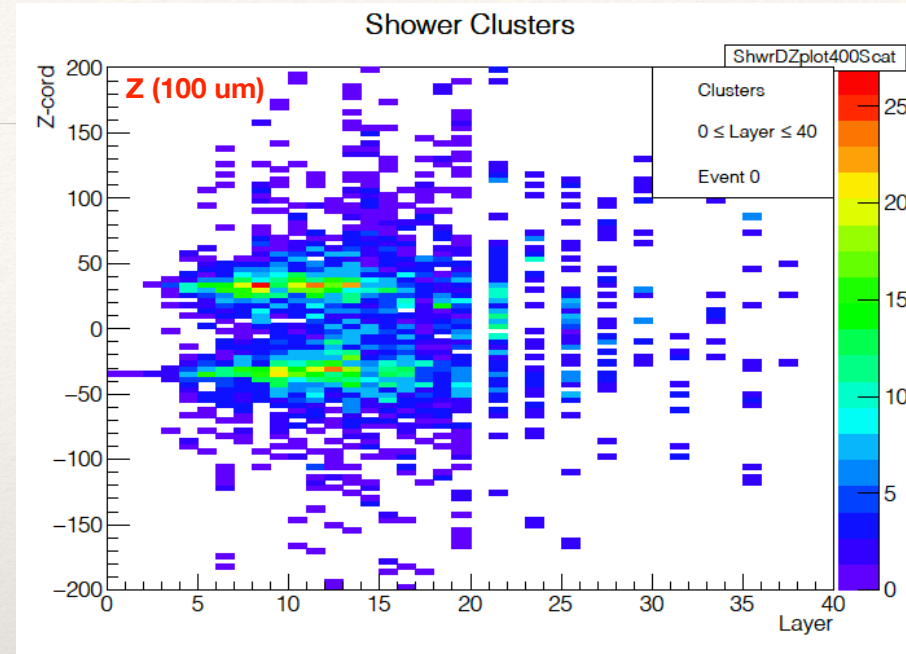
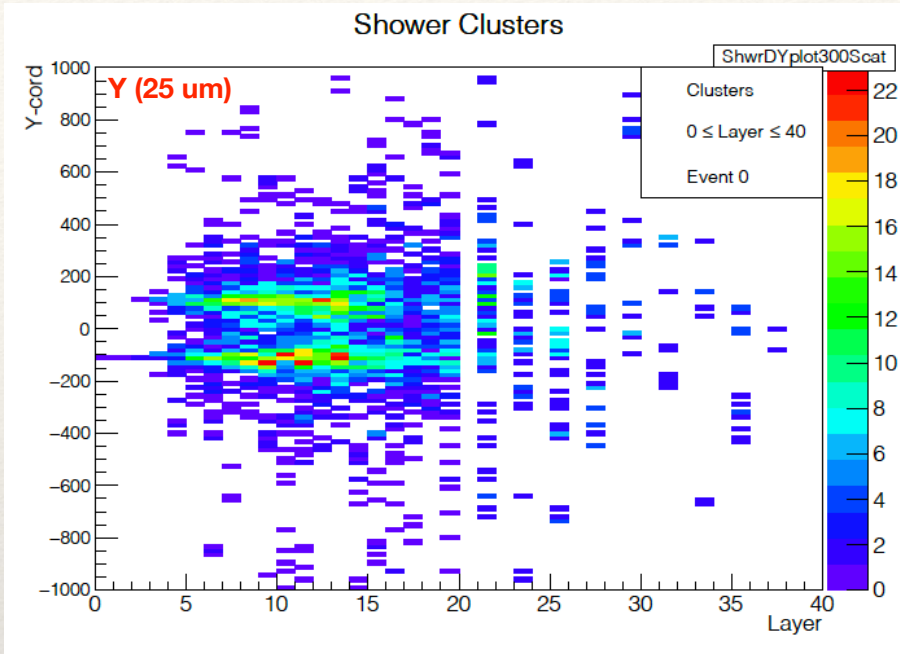
40 GeV $\pi^0 \rightarrow$ two 20 GeV γ 's



Vertical bin
400 μm

J. Brau - 21 August 2023

SiD Digital ECAL based on Silicon MAPS



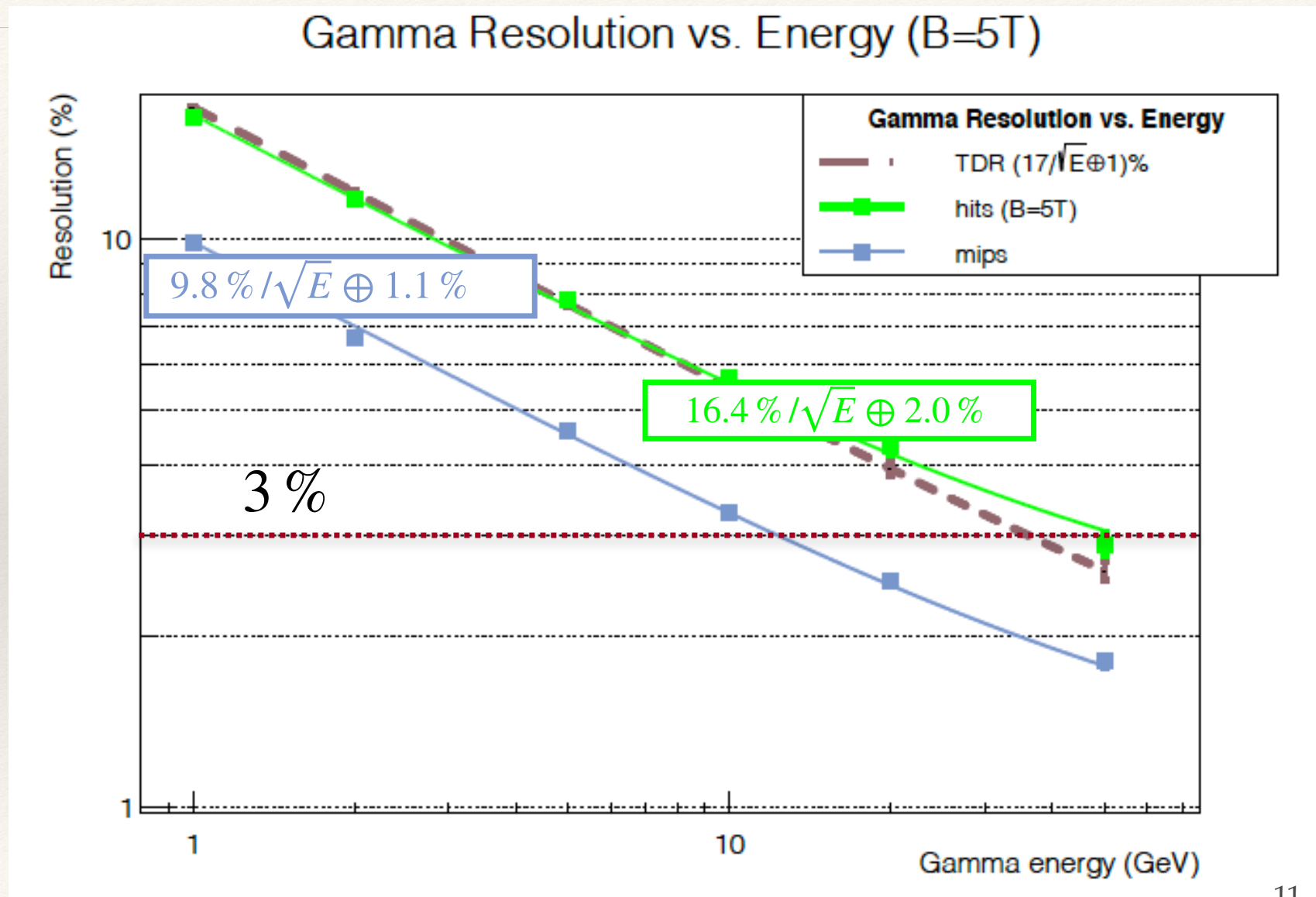
Resolution vs. Energy (hits and mips)

Resolution vs. Energy
(hits and mips)

Hits are active pixels
& Mips count each
charged particle in
sampling gap just
once (truth).

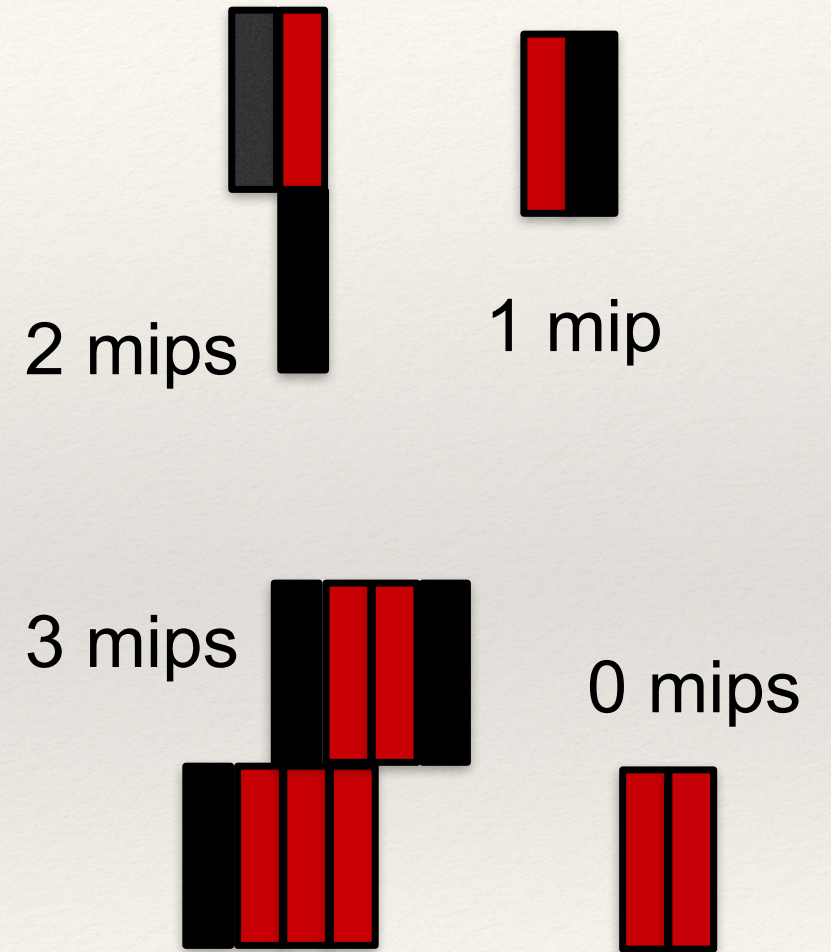
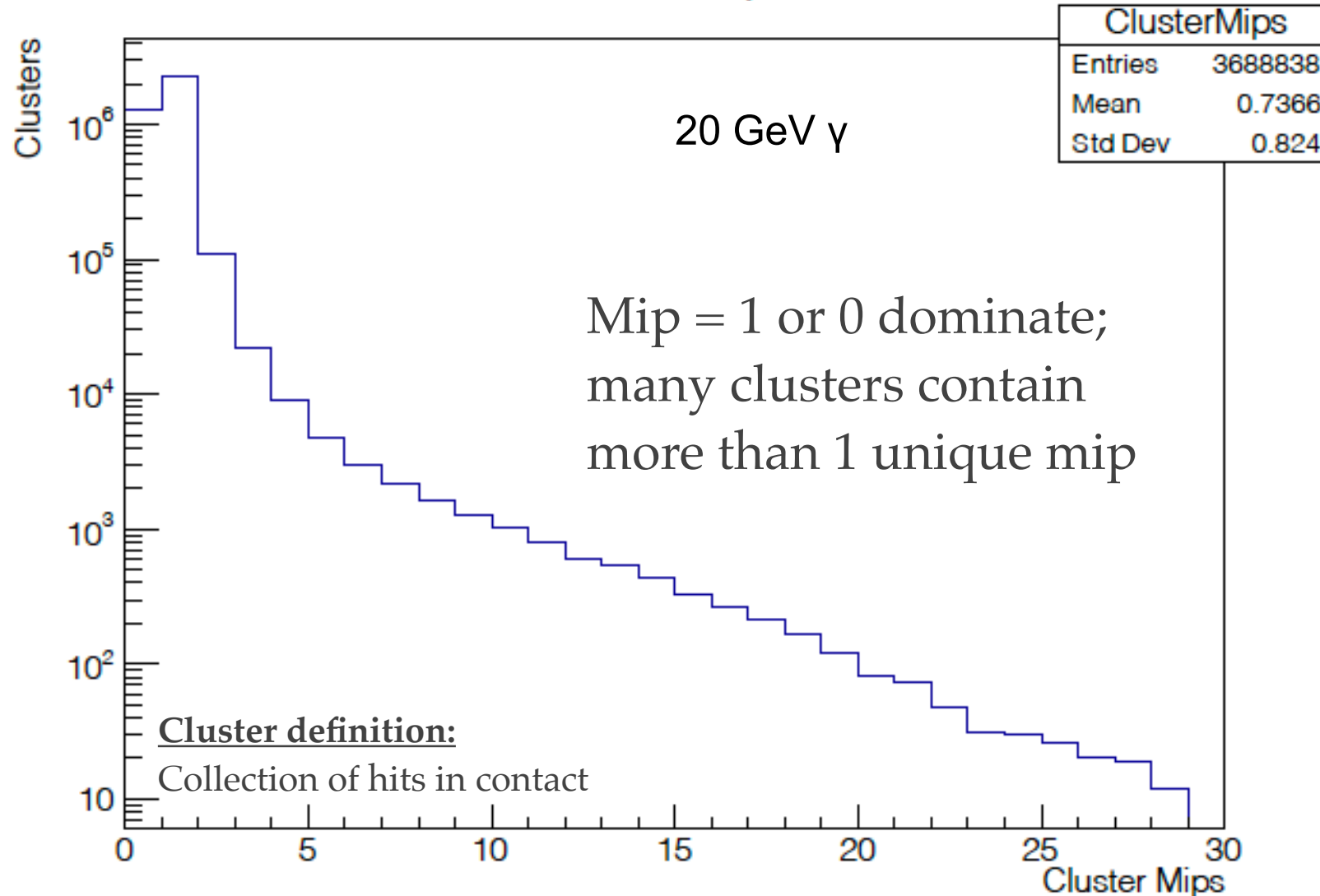
Resolution can be
improved!

TDR =
arXiv:1306.6329 [physics.ins-det]

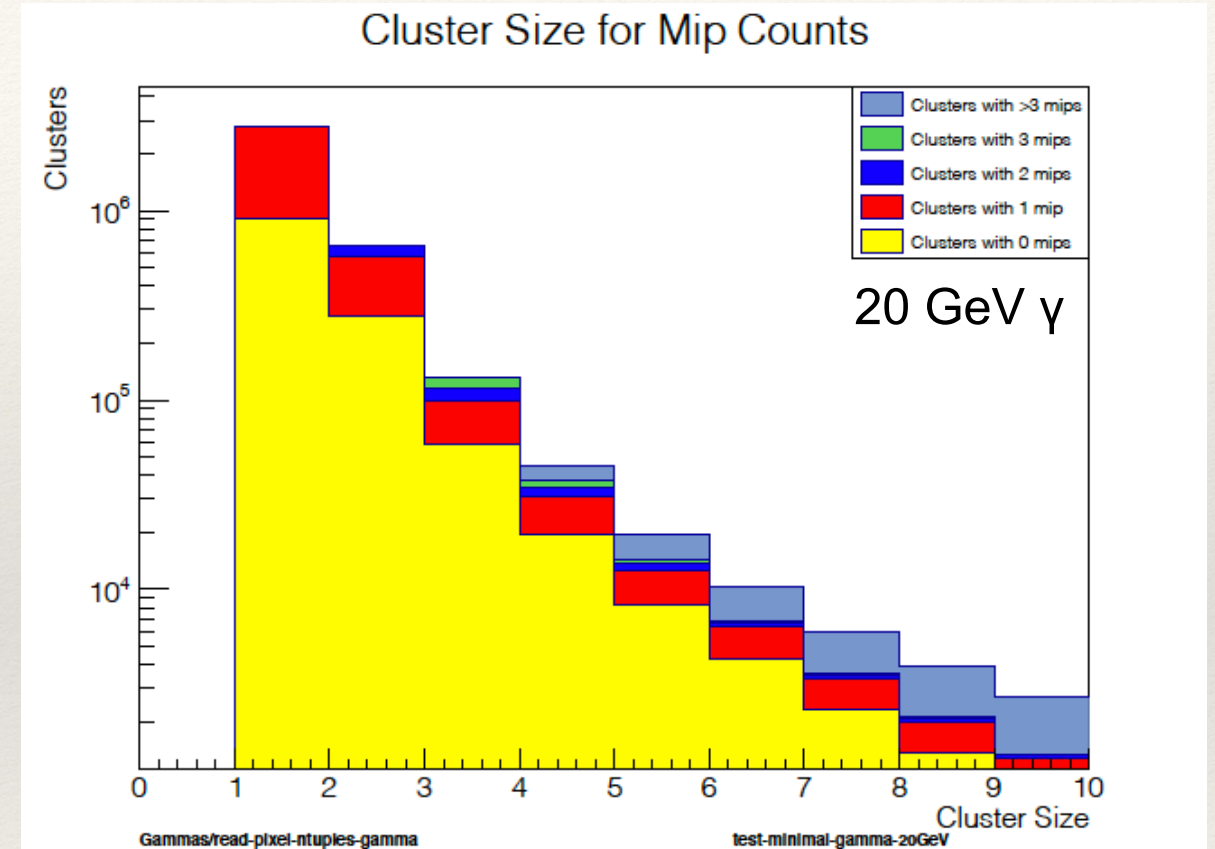
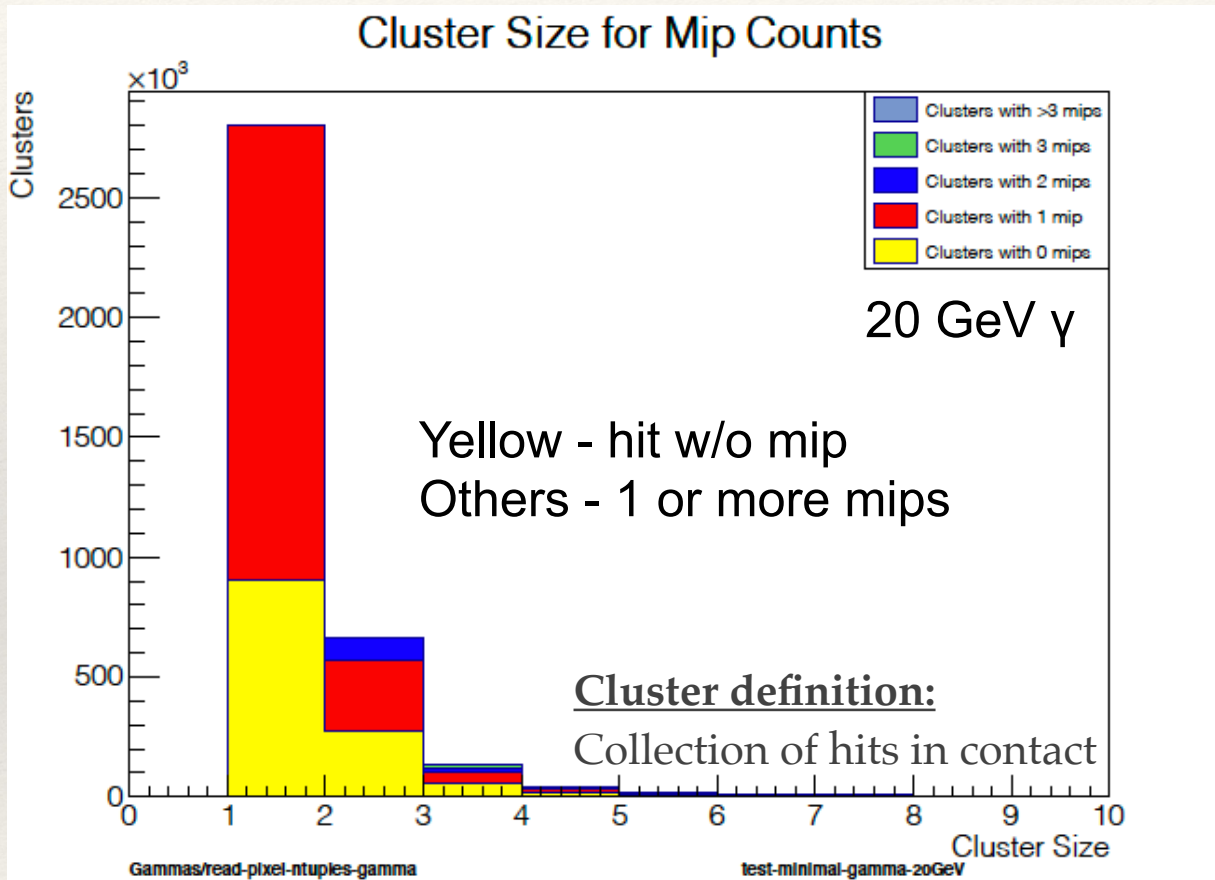


Mips per cluster

Cluster Mips -



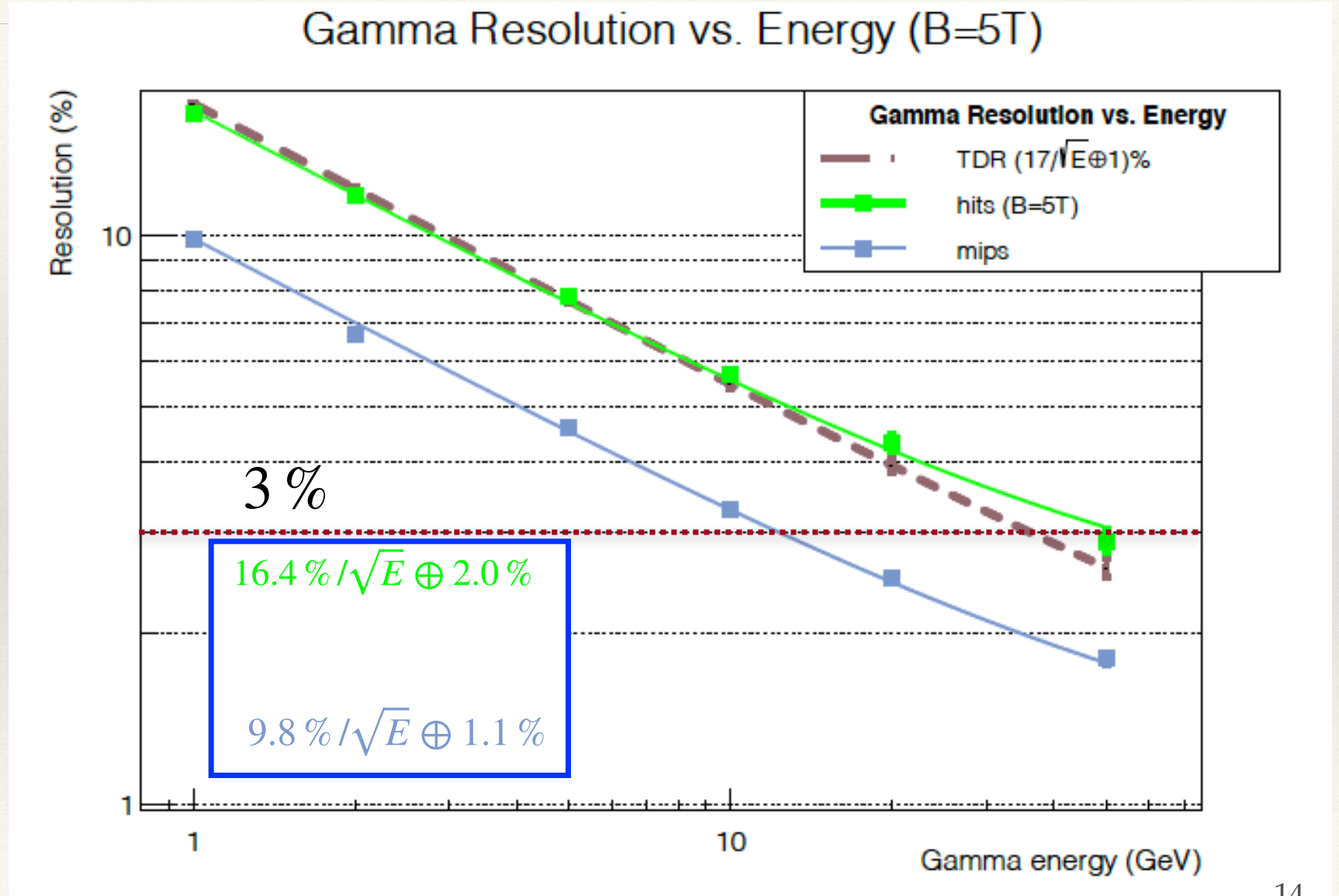
Cluster summary (20 GeV γ)



Cluster count is closer to mip count, reducing fluctuations from multiple hits.

Resolution vs. Energy (hits/clusters/mips)

Resolution vs. Energy
(hits and mips)

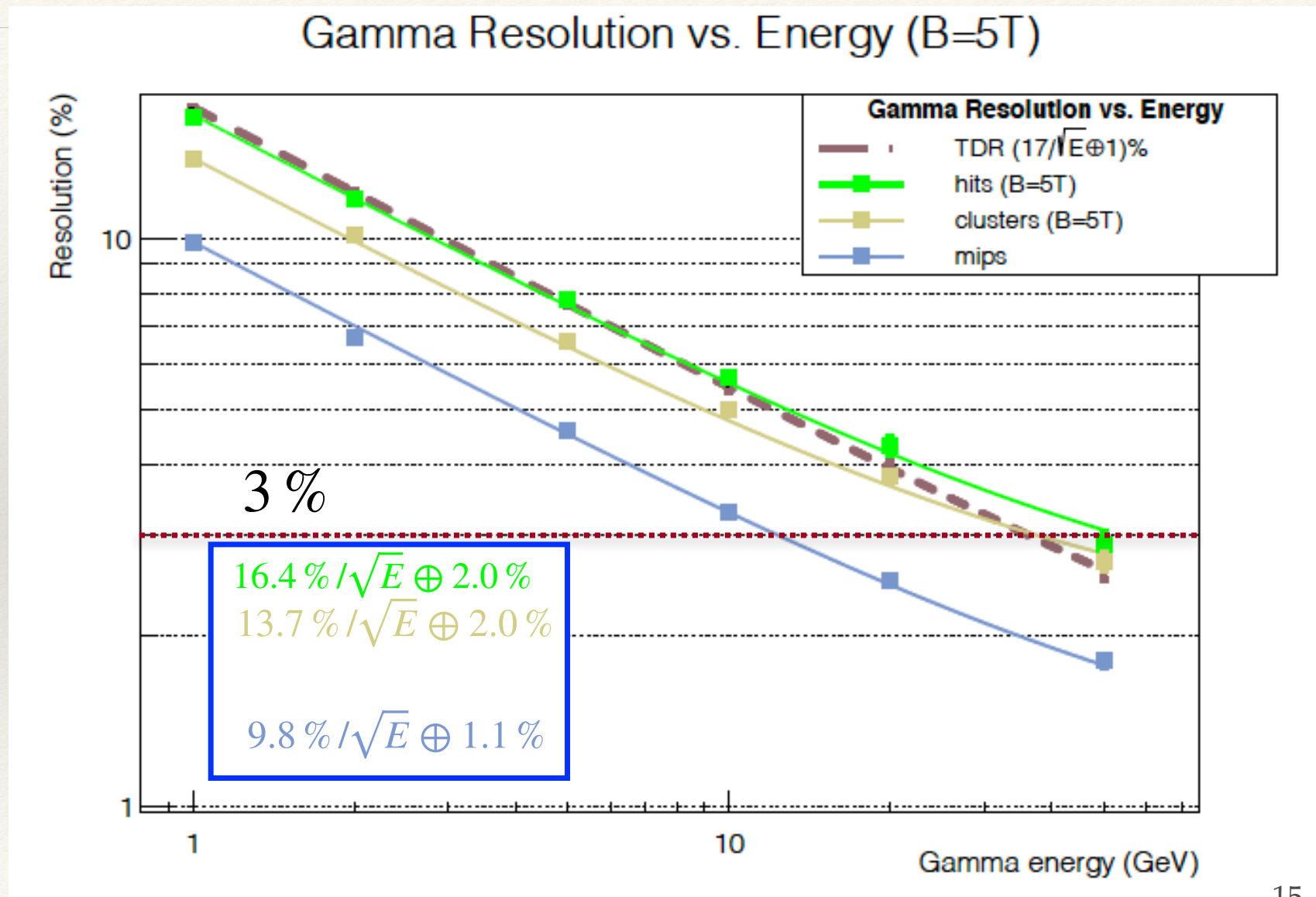


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Resolution vs. Energy (hits/clusters/mips)

Resolution vs. Energy
(hits / clusters / mips)

Simple cluster
performance is better
than hit counting.



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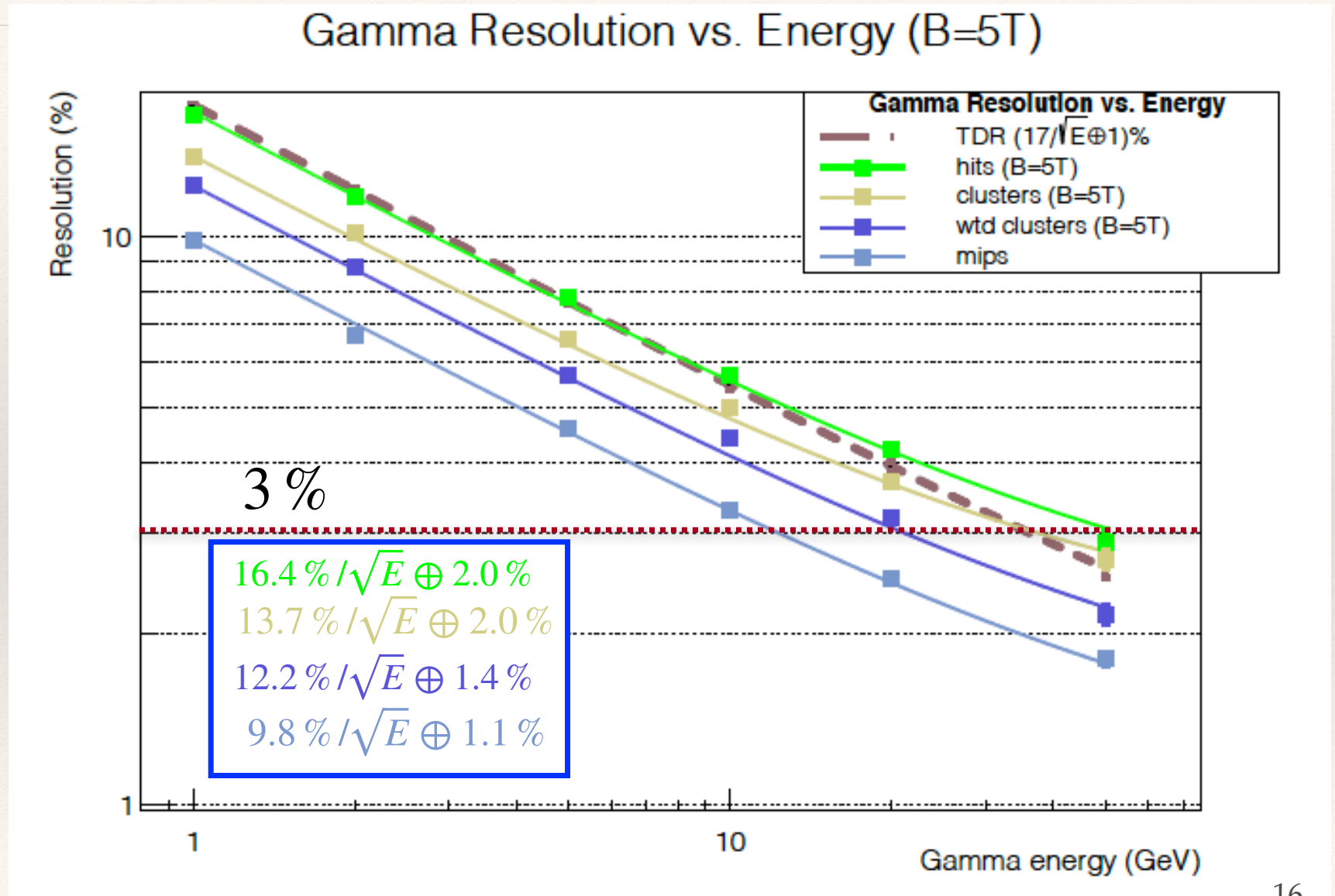
Resolution vs. Energy (hits/clusters/mips)

Resolution vs. Energy
(hits / clusters / mips) &
weighted clusters.

Simple cluster
performance is better
than hit counting.

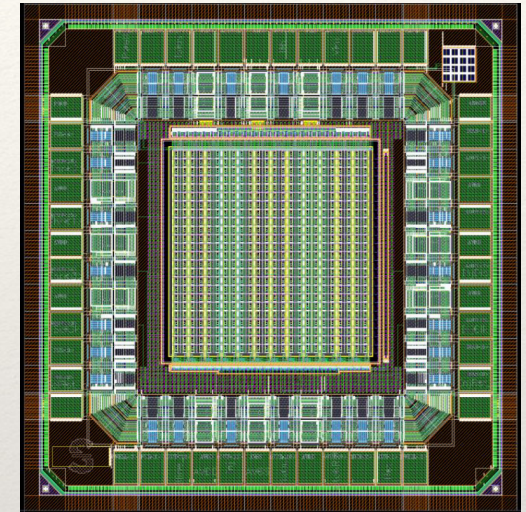
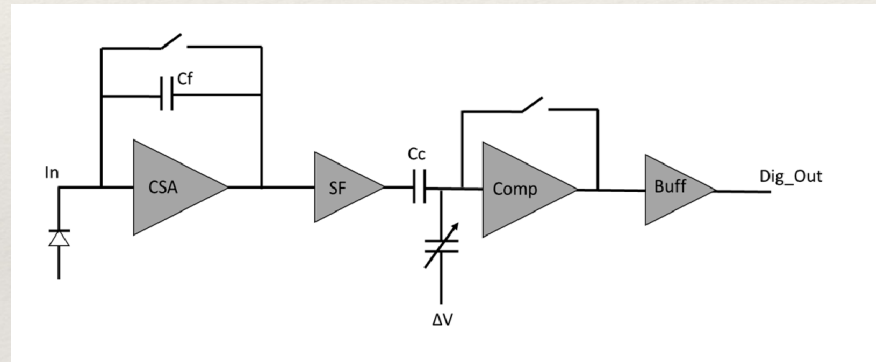
When cluster properties
are taken into account
with weighting,
performance improves.

TDR =
arXiv:1306.6329 [physics.ins-det]



NAPA_p1: NAnosecond Pixel for large Area sensors – Prototype 1

- ❖ Design in Tower Semiconductor 65 nm imaging technology, capitalizing on the CERN WP1.2 efforts over a decade of sensor optimization.
- ❖ The prototype design submitted with a total area 5 mm x 5 mm and a pixel of 25 μm x 25 μm , to serve as a baseline for sensor and pixel performance.



Layout of MAPS SLAC prototype for WPI.2 shared submission

Key pixel elements

- ❖ Charge Sensitive Amplifier (CSA) with a synchronous reset, which can be powered down during inactive time
- ❖ A comparator with auto-zero technique, removing the need for per-pixel threshold calibration

Summary



- ❖ MAPS has great a potential for the Higgs factory linear collider requirements
 - ❖ for ECal, as well as vertex detector and tracking.
- ❖ Simulation studies of the ECal performance demonstrates better than ILC TDR specs, achieving
$$12.2\% / \sqrt{E} \oplus 1.4\%$$
- ❖ High granularity and timing adds to the performance.
- ❖ Low sensor capacitance of 2-3 fF in Tower Semiconductor 65nm technology, improving power efficiency by at least 2 order of magnitude with respect to hybrid detectors.
- ❖ Simulations of NAPA_p1 show that it is possible to achieve a time resolution ~ 1 ns-rms with reasonably low power consumption of $115 \text{ mW} / \text{cm}^2 \times \text{DutyCycle}$, where DutyCycle for linear colliders $< 1\%$
- ❖ NAPA-p1 characterization is underway. Results should be available soon.
- ❖ Support needed to continue this promising development effort.